

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Gabric, *et al.* Docket No.: INF 2006 VJ 33543 US
Serial No.: 10/586,788 Art Unit: TBD
Filed: July 21, 2006 Examiner: TBD
I.A. Filing Date: January 22, 2005 I.A. No.: PCT/DE2005/000088
For: Plasma Excited Chemical Vapor Deposition Method,
Silicon/Oxygen/Nitrogen-Containing-Material and Layered Assembly

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO NOTIFICATION OF MISSING REQUIREMENTS UNDER
35 U.S.C. 371

Dear Sir:

In response to the Notification of Missing Requirements under 35 U.S.C. 371 having a mailing date of July 1, 2008, Applicant respectfully submits a copy of the signed Declaration for Patent Application, Power of Attorney & Designation of Correspondence Address and an English Translation of the specification.

The Commissioner is hereby authorized to charge the required \$130 late oath surcharge and the \$130 fee for an English translation after 30 months from the priority date to Deposit Account No. 50-1065. Please charge any additional fees and credit any overpayments to the same.

Please contact Applicant's attorney with any questions regarding this matter.

Respectfully submitted,



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Date

9/2/08

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